



STALLMAN & POLLOCK LLP  
353 Sacramento Street, Suite 2200  
San Francisco, CA 94111  
(415) 772-4900

In re Patent Application of: Michael Weber-Grabau et al.

Atty Docket No. TWI-31000

Application No.: 09/927,103

Filed: August 10, 2001

For: OPTICAL CRITICAL DIMENSION METROLOGY SYSTEM INTEGRATED INTO  
SEMICONDUCTOR WAFER PROCESS TOOL

M/S AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Transmittal herewith is an amendment in the above-identified application.

The fee has been calculated as shown below.

	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL	44	MINUS	44	0	x \$18 =	\$0
INDEP.	6	MINUS	6	0	x \$86 =	\$0
FIRST PRESENTATION OF MULTIPLE DEP CLAIMS					+ \$290	\$0
					TOTAL	\$0

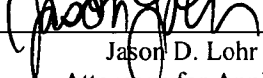
Small Entity 50% Filing Fee Reduction (if applicable) \$0

- \* If the entry in Col. 1 is less than the entry in Col. 2, write "0" in Col. 3  
\*\* If the "Highest Number Previously Paid For" IN THIS SPACE is less than 20, write "20" in this space.  
\*\*\* If the "Highest Number Previously Paid For" IN THIS SPACE is less than 3, write "3" in this space. The "Highest Number Previously Paid For" (Total or Independent) is the highest number found from the equivalent box in Col. 1 of a prior amendment or the number of claims originally filed.)

- ☒ No additional fee is required.
- ☒ Attached for filing is a Change of Attorney or Agent's Address in Application (37 CFR 1.8(a)).
- ☒ Please charge any additional fees, including any fees necessary for extensions of time or credit overpayment to Deposit Account No. 50-1703, under Order No. TWI-31000.  
**A duplicate copy of this sheet is enclosed.**
- ☐ Petition for extension of time. The undersigned attorney of record hereby petitions for an extension of time pursuant to 37 C.F.R. § 1.136(a), as may be required, to file this response.

STALLMAN & POLLOCK LLP

Dated: May 14, 2004

By:   
Jason D. Lohr (Reg. No. 48,163)  
Attorneys for Applicant(s)

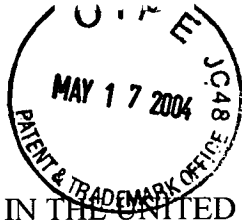
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Dated: May 14, 2004

By:   
Georgia K. Stith

09/927,102



-1-

PATENT

AF 2877  
Ifw

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Michael Weber-Grabau, et al.

Application No.: 09/927,102

Filed: August 10, 2001

For: CRITICAL DIMENSION METROLOGY  
SYSTEM INTEGRATED INTO  
SEMICONDUCTOR WAFER PROCESS  
TOOL

Group Art Unit: 2877

Examiner: Richard A. Rosenberger

**RESPONSE TO FINAL OFFICE  
ACTION MAILED MARCH 17, 2004**

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Box 1450, Alexandria, VA 22313-1450 on May 14, 2004.  
STALLMAN & POLLOCK LLP

Dated: 05/14/2004

By:

Georgia K. Stith  
Georgia K. Stith

Sir:

In response to the Final Office Action mailed March 17, 2004, please amend the above-identified application as follows:

**Amendment to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 11 of this paper.

Atty Docket No.: TWI-31000

Copied from 09927103 on 07/15/2004